



Development of Cryogenic Thermal Detectors for Sub-GeV Dark Matter

Noemie Bastidon¹, Clarence Chang², Enectali Figueroa-Feliciano¹, Ziqing Hong¹, Valentine Novosad², **H Douglas Pinckney**^{1,3}, Gensheng Wang², Volodymyr Yefremenko²



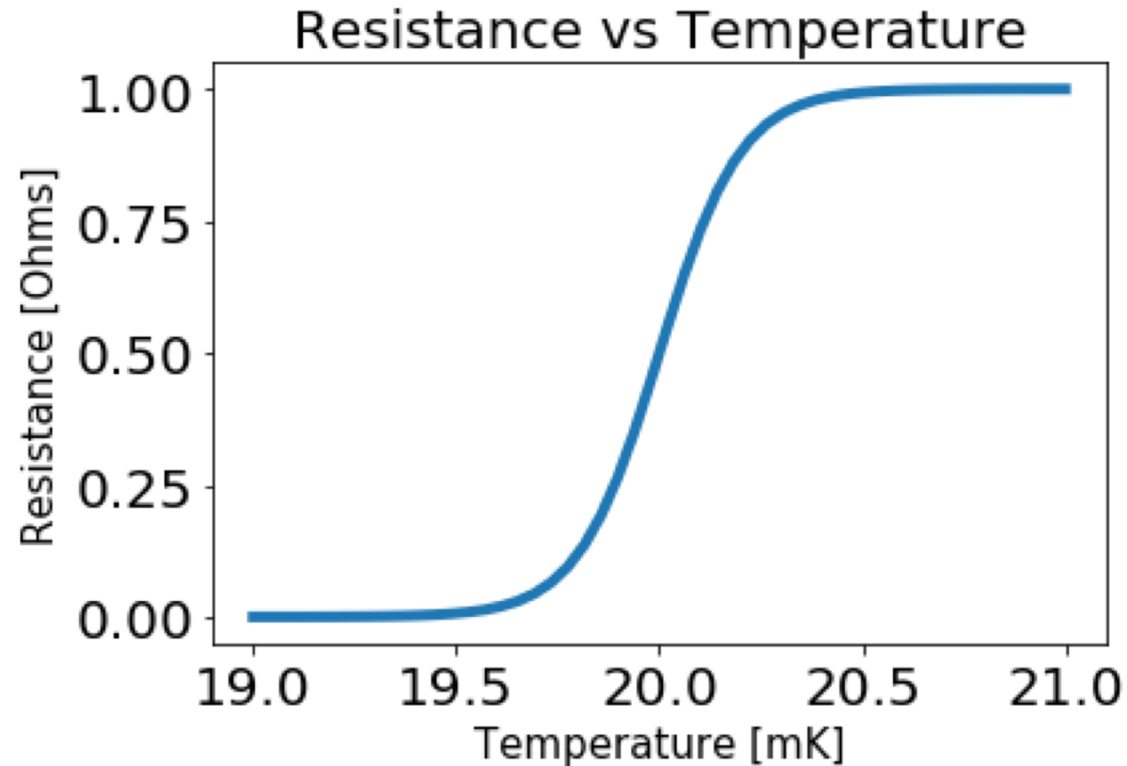
1. Northwestern University
2. Argonne National Lab
3. University of Massachusetts Amherst

Motivation

- Low mass dark matter ($M_{\text{DM}} < 1 \text{ GeV}$) is an interesting problem to solve
- Could be detected via collision with Silicon nuclei with detector threshold of around 10 eV
- Will describe the design/fabrication efforts of such a cryogenic detector

Transition Edge Sensor (TES) Basics

- Use the sharp temperature-resistance transition of a superconductor to convert thermal to electrical signals



Using the TES

- How can we reach 10 eV threshold with this method?
 - Low heat capacity
 - **Lowers exposure mass**

Using the TES

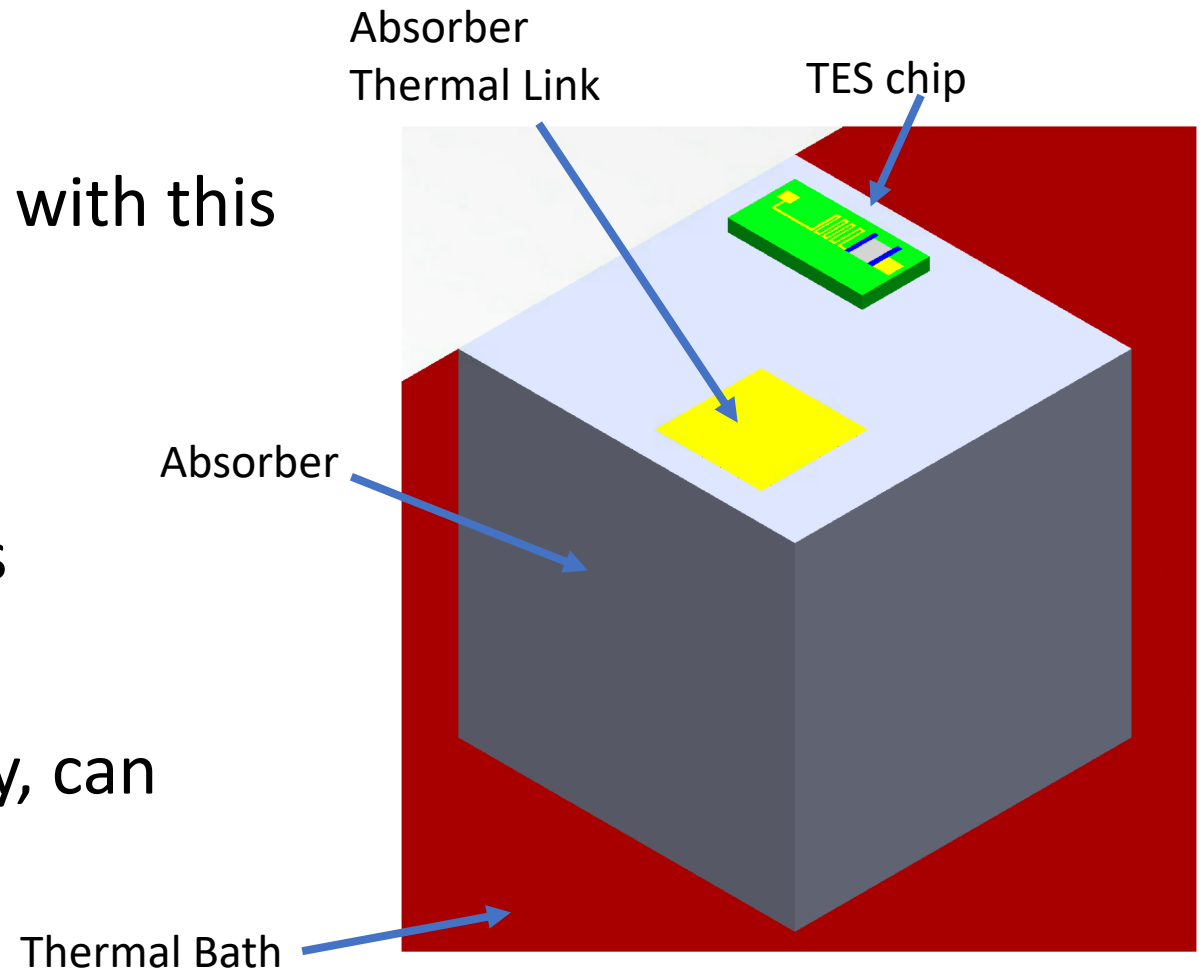
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- Idea: Use many separate absorbers
- Challenge: Tedious fabrication

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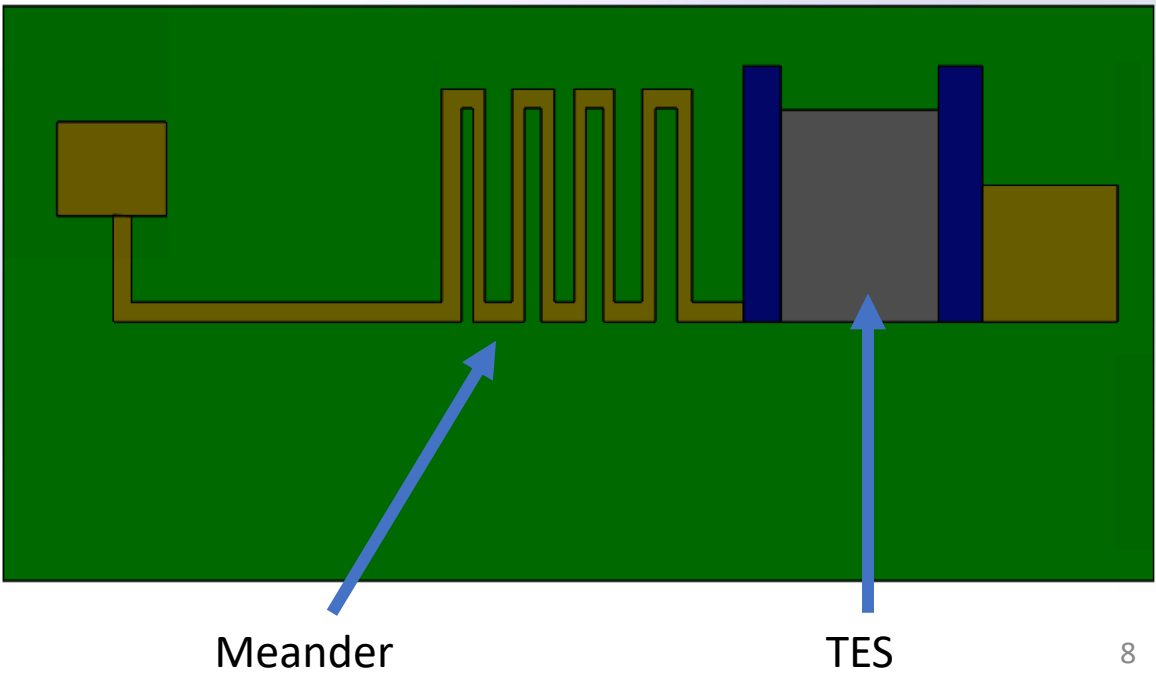
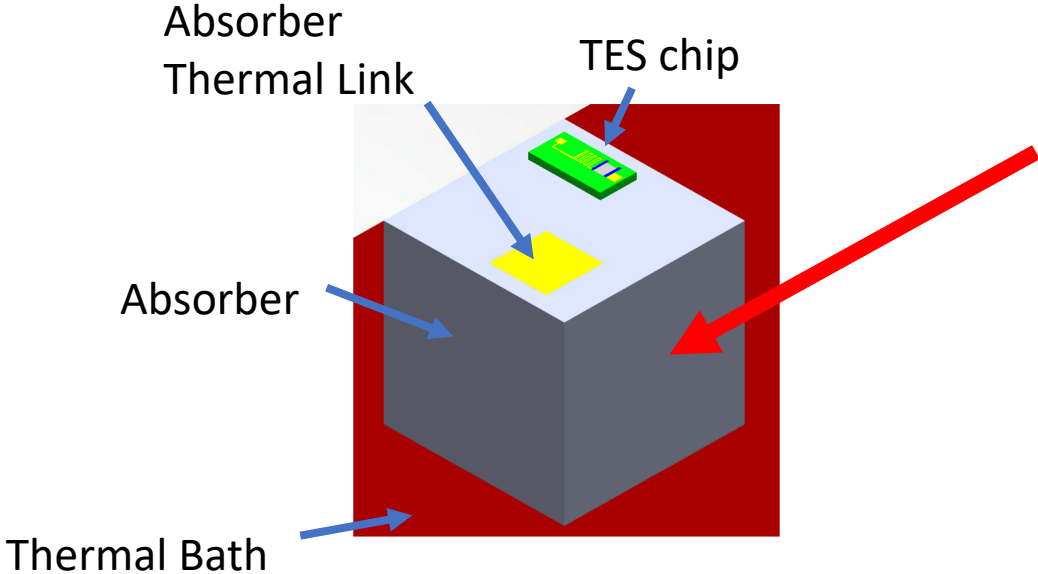
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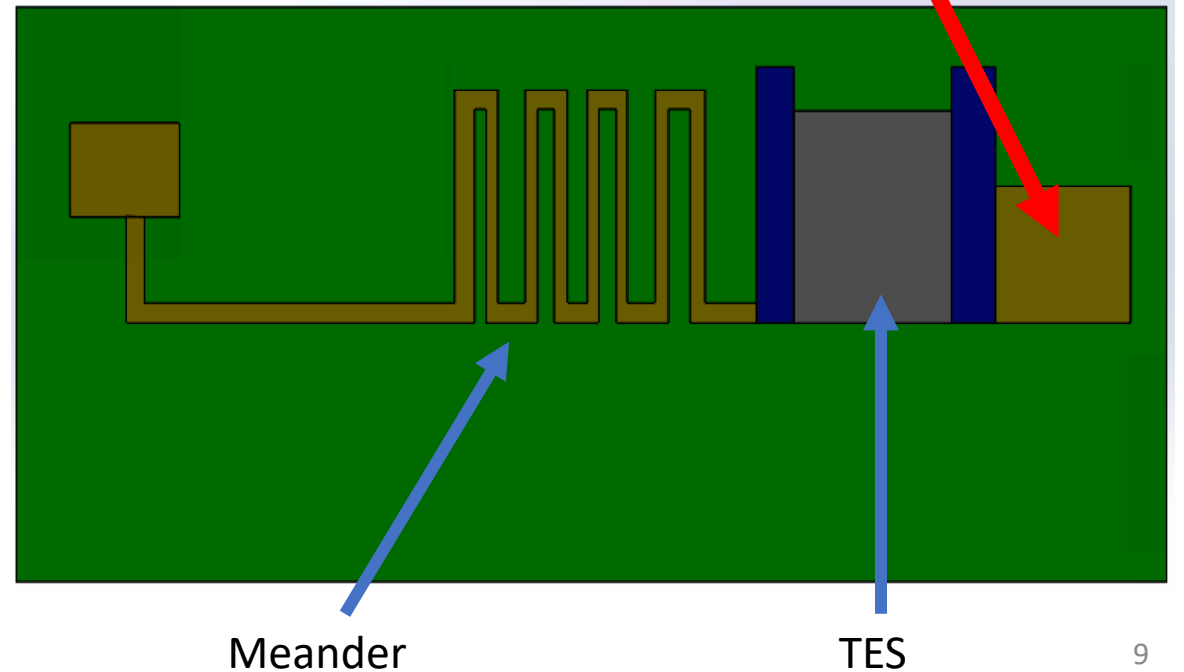
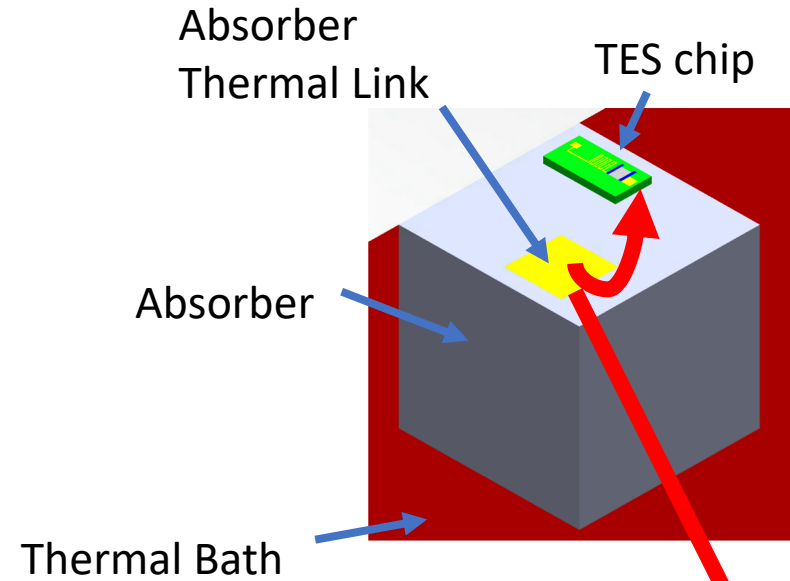
Thermal Circuit

1. Energy absorbed



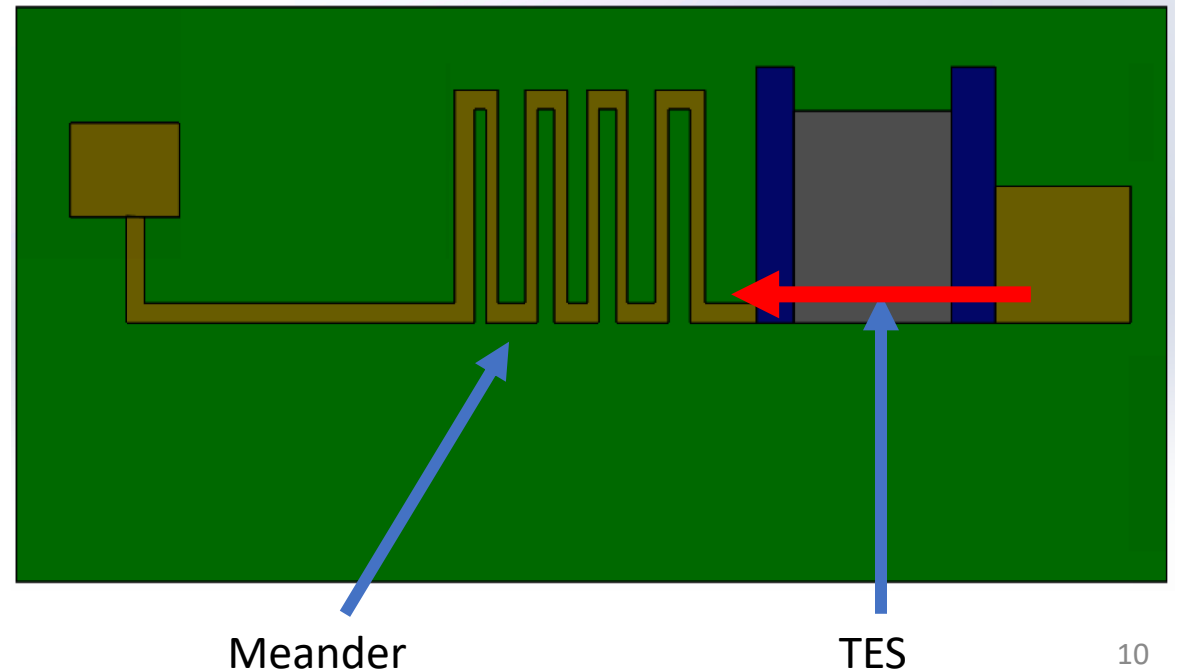
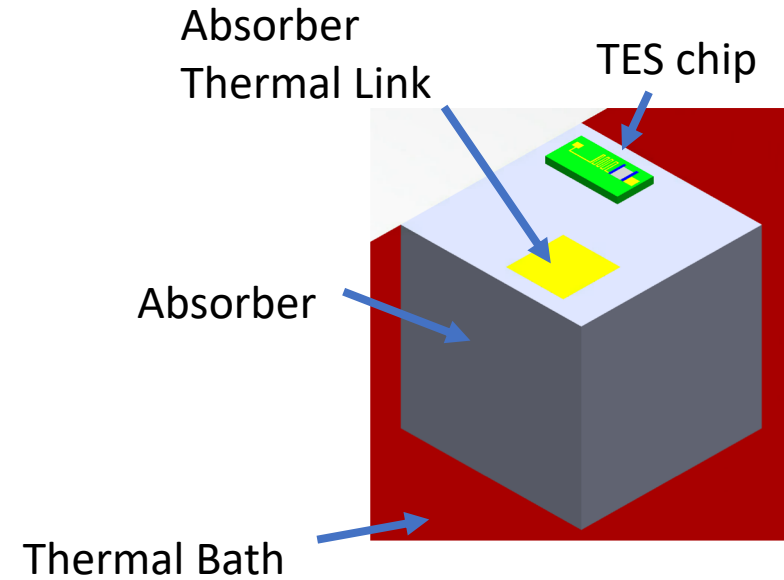
Thermal Circuit

1. Energy absorbed
2. Energy flows through absorber gold pad and wire bond to thermal chip



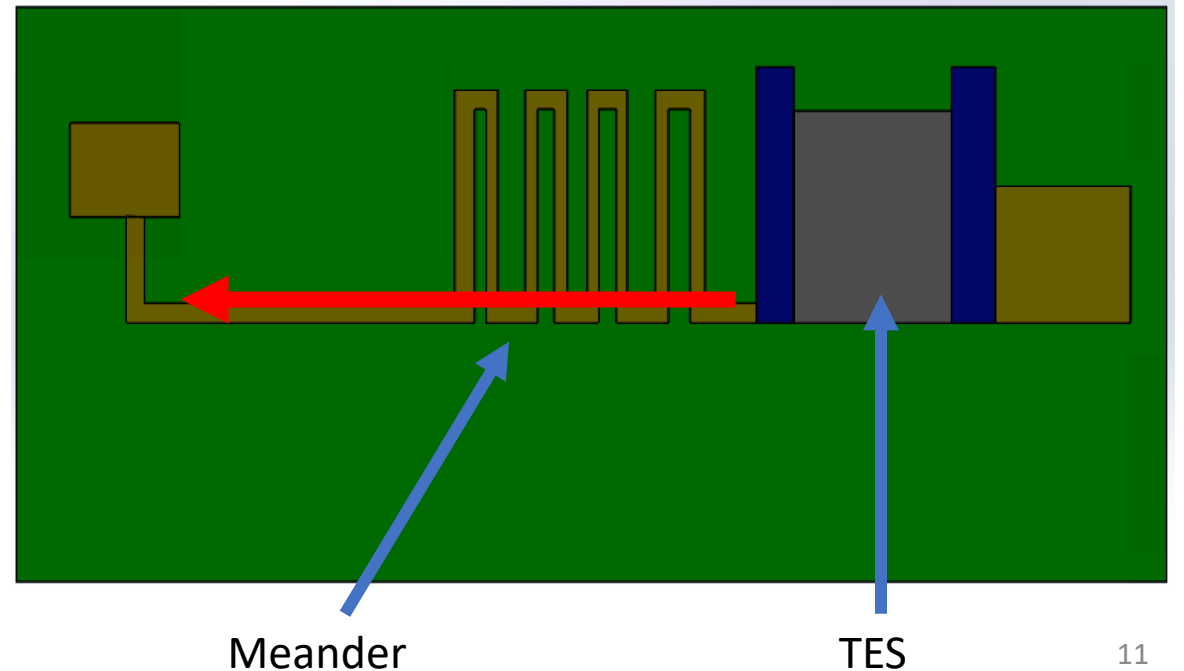
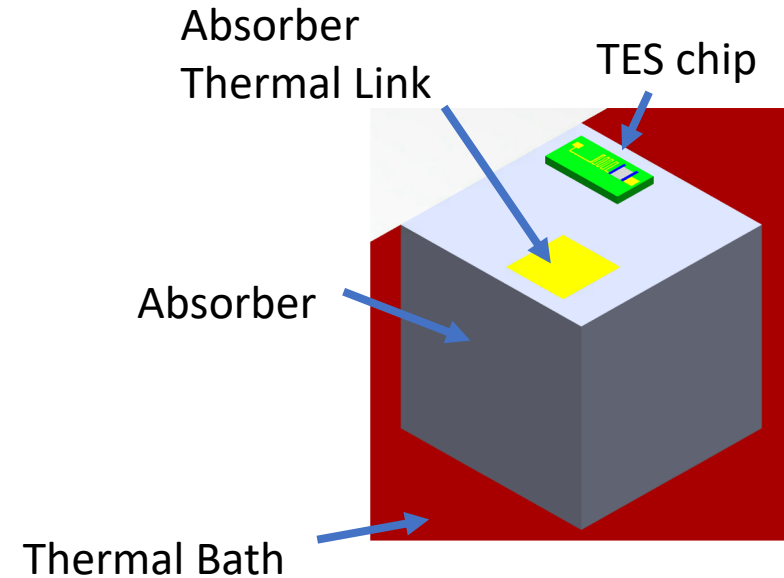
Thermal Circuit

1. Energy absorbed
2. Energy flows through absorber gold pad and wire bond to thermal chip
3. Energy flows through TES



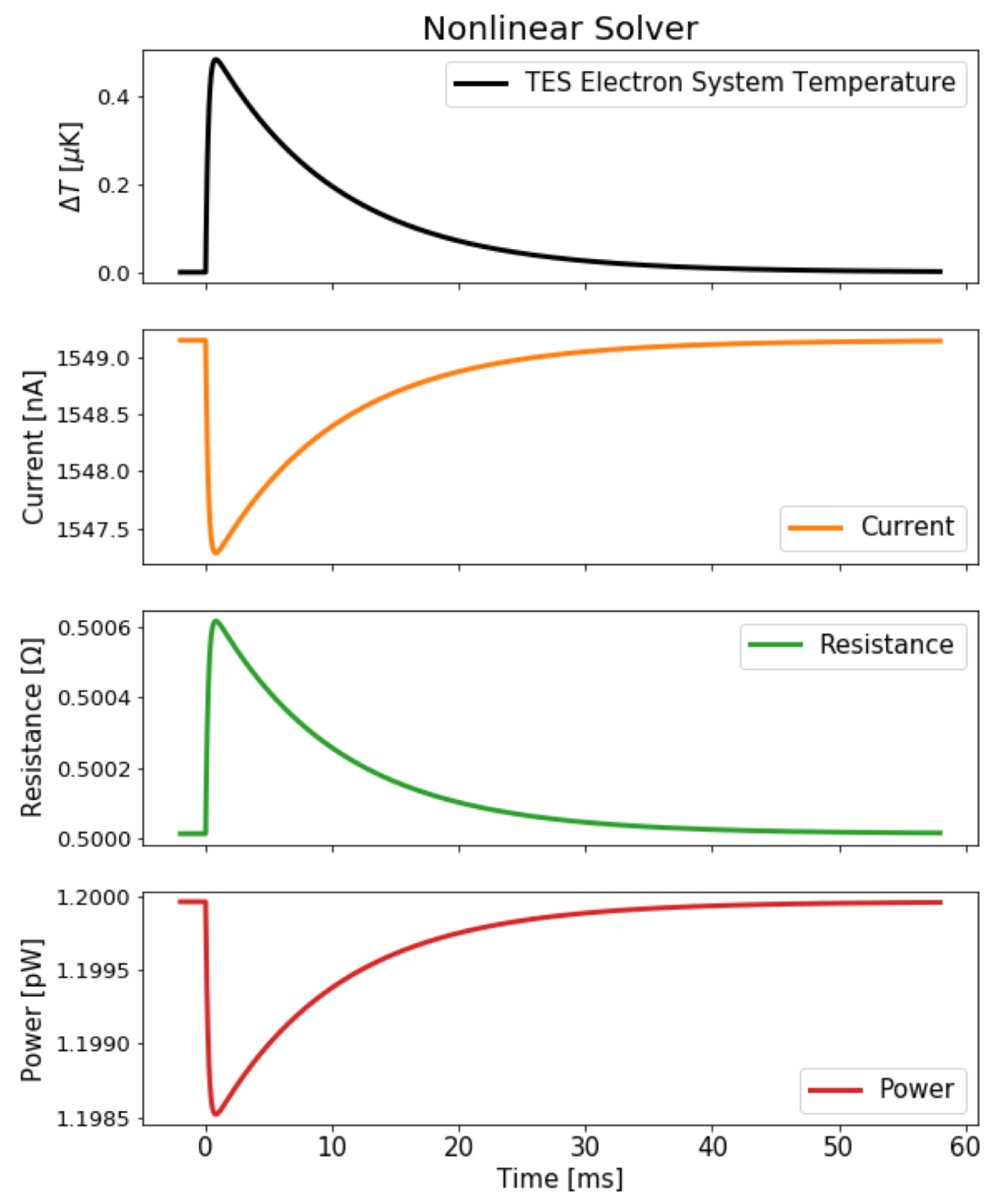
Thermal Circuit

1. Energy absorbed
2. Energy flows through absorber gold pad and wire bond to thermal chip
3. Energy flows through TES
4. Energy flow out of TES controlled by geometry of gold meander



Theoretical Results

- 5 eV threshold
 - Tungsten TES
 - 1 cm³ Silicon Absorber
 - 20 mK transition temperature

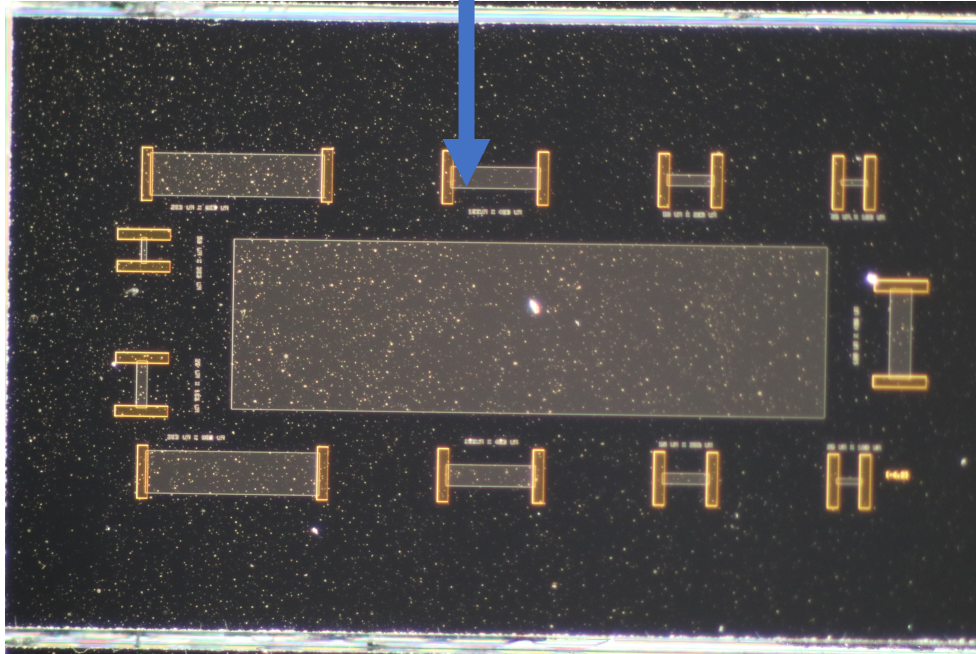


Practical Implementation

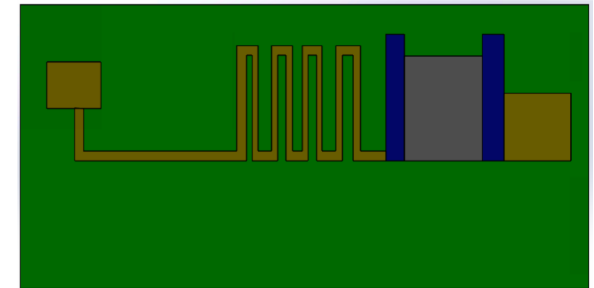
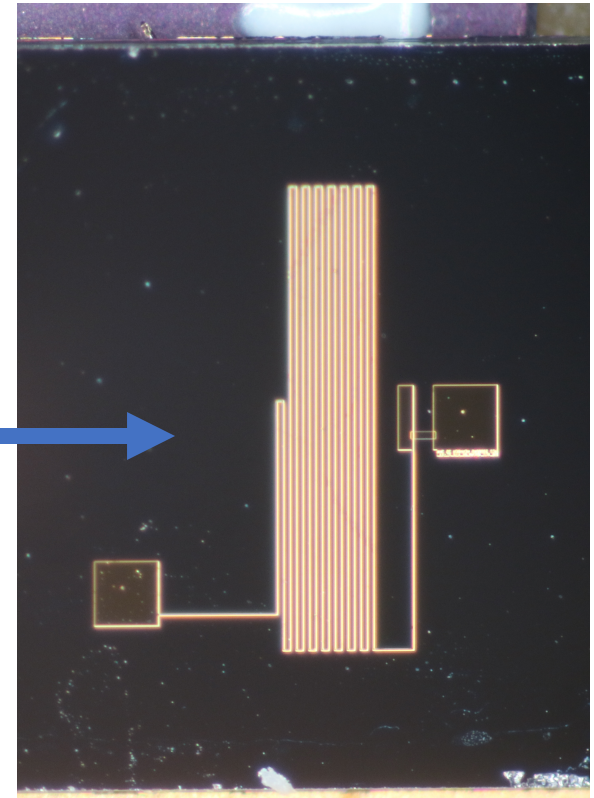
- Create a mask for initial tests
- Current testing apparatus has base temperature around 50 mK
 - Aim for transition temperature of around 85 mK
 - Mask design has contingency for transition temperatures of 60 mK – 100 mK
- Mask prepares for multiple absorber materials
 - Silicon
 - Germanium
 - Zinc
 - No absorber

First Tests

- Transition temperature check
 - Observed at 85 mK and 80 mK



Transition temperature test structure



Future Tests and Goals

- Future Tests:
 - Measure gold thermal conductance
 - Observe pulses
 - Compare with the model
- Goal:
 - Move towards the lower transition temperature design for better performance

Conclusions

- Cryogenic thermal detectors can theoretically reach the sensitivity necessary for sub-GeV dark matter searches
- High temperature proof-of-concept tests are underway
- Low temperature tests should be in the near future

Acknowledgments

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References

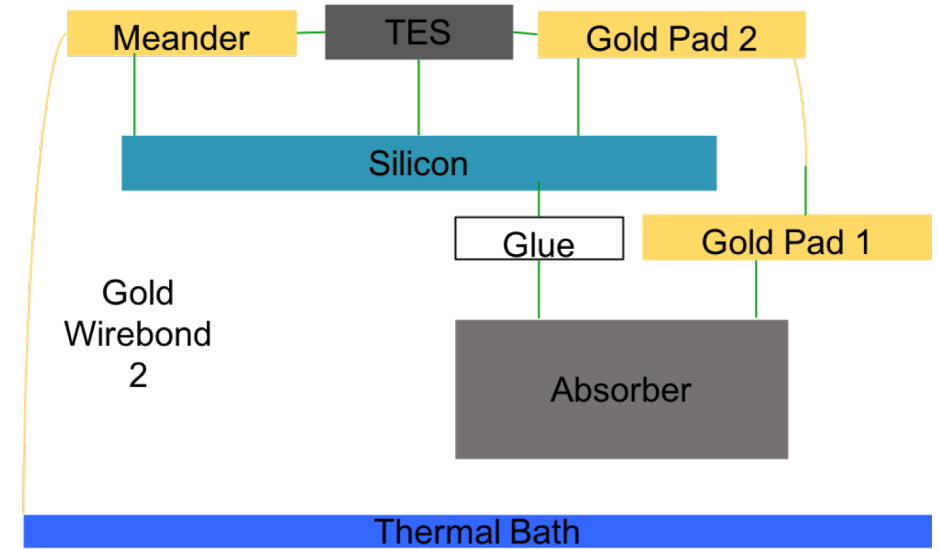
- E. Figueroa-Feliciano. *Complex microcalorimeter models and their application to position-sensitive detectors*. JAP (2006)
- M. Pyle et al. *Optimized designs for very low temperature massive calorimeters*. (2015) **arXiv:1503.01200v2**

Bonus Slides

Model Parameters

Connection	Thermal Conductance [W/K]
Absorber - Glue	1×10^{-9} [14]
Absorber - Gold Pad 1	2×10^{-8} [5]
Glue - Die	1×10^{-9} [14]
Die - Gold Pad 2	1×10^{-10} [5]
Die - TES	6×10^{-12} [5]
Die - Meander	1×10^{-9} [5]
Gold Pad 1 - Wire Bond 1	7×10^{-6} [19]
Wire Bond 1 - Gold Pad 2	7×10^{-6} [19]
Gold Pad 2 - TES	5×10^{-6} [19]
TES - Meander	2×10^{-5} [19]
Meander - Wire Bond 2	8×10^{-11}
Wire Bond 2 - Bath	2×10^{-6} [19]

Component	Heat Capacity [J/K]
Absorber	5×10^{-12} [15]
Glue	7×10^{-15} [18]
Gold Pad 1	1×10^{-11} [16]
Wire Bond 1	1×10^{-11} [16]
Gold Pad 2	5×10^{-14} [16]
Die	2×10^{-14} [15]
TES	5×10^{-14} [17]
Meander	4×10^{-13} [16]
Wire Bond 2	1×10^{-11} [16]

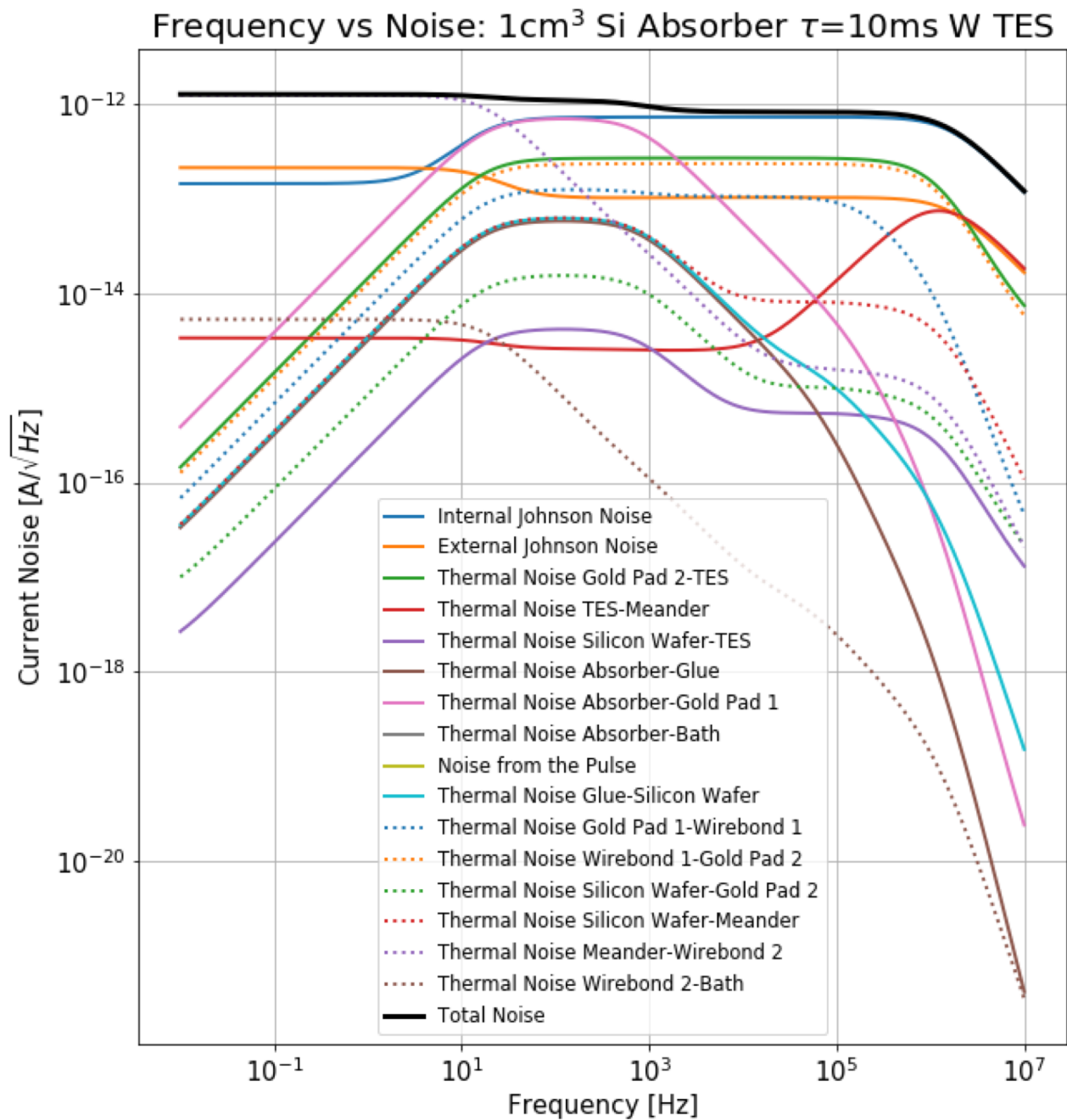


Electrical Components

L : 1.0e-7
 Rl : 0.02
 alpha0 : 100.
 beta0 : 1.
 Rn : 1.
 Ccap : 5.0e-12
 I0_NL : 1.73165509123e-06
 electronics_noise : 3.0e-11
 one_over_f_noise : 3.0e-11
 one_over_f_gamma : 0.5
 lowpass : 3000000.0
 lowpasspoles : 1.0

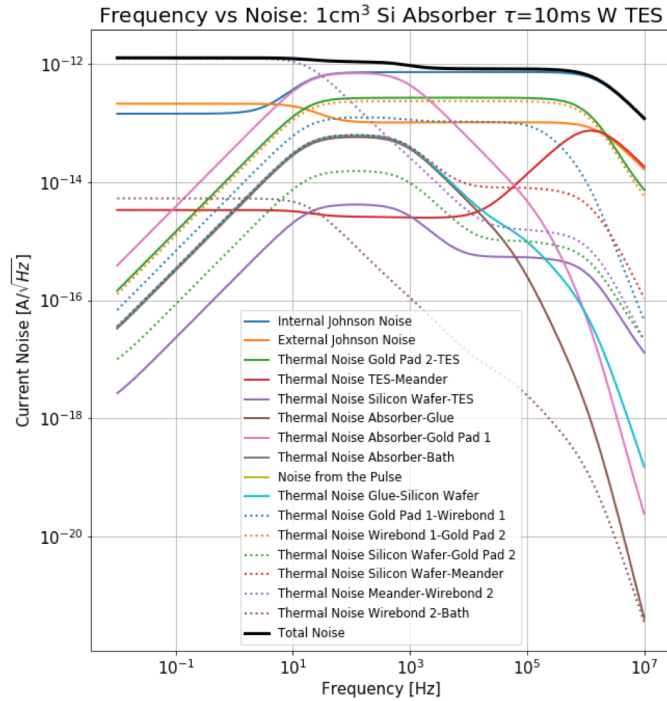
#Inductor in Thevenin Equivalent [Henries]
 #Load/Shunt Resistor [Ohms]
 #Temperature Sensitivity [Unitless]
 #Current sensitivity [Unitless]
 #normal resistance of the TES [Ohms]
 #Capacitor in Thevenin equivalent Circuit [Farads]
 #[Amps], taken from the nonlinear solver at large time after equilibrium had been reached
 # extra electronics noise at a constant level [A/sqrt Hz]
 # one over f noise coefficient
 # exponent for one over f noise
 # frequency of low pass filter[Hz]
 #number of poles in filter [n/a]

Noise Spectrum



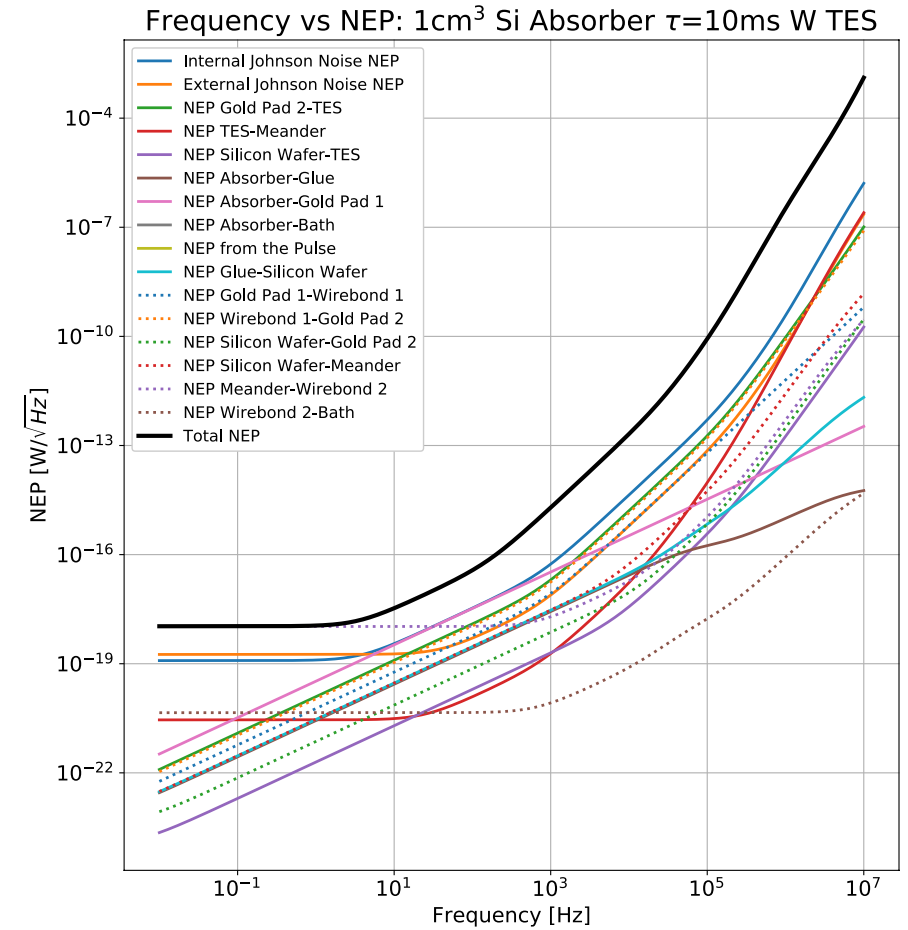
Resolution Calculation

$$\text{Resolution}_{\text{FWHM}} = 2.35 \left(\sqrt{\int_0^{\infty} \frac{4df}{\text{NEP}(f)^2}} \right)^{-1}$$



+

Responsivity



Mask Design Optimization Results

Material	Temperature [mK]	Time Constant [ms]	Resolution [eV FWHM]
Silicon	60	10	20
	80	19	41
	100	40	71
Germanium	60	25	34
	80	40	81
	100	59	163
Zinc	30	10	32
	60	51	222
	80	101	539
	100	102	715
None	60	0.05	1.9
	80	0.12	3.2
	100	0.25	5.2

$$\text{Threshold} = 7.5 \left(\frac{\text{Resolution}_{\text{FWHM}}}{2} \right)$$

Absorber Heat Capacity at 20 mK

	Silicon	Zinc	Sodium Iodide
1cm ³	5×10^{-12} J/K	5×10^{-11} J/K [9]	8×10^{-11} J/K [21]
0.4cm ³	2×10^{-12} J/K	x	x